

## Main Options of A8 Prober



- OCR wafer ID reader
- Chuck: high/low/normal temperature
- Support 50μm wafer
- Support Bernoulli arm and chuck
- 3KV high voltage, 300A large current
- Triaxial chuck, pA leakage current
- Real time map data
- One touch contact probing
- PMAI: Probe Mark Auto-Inspection
- PLV: Prober Log Viewer
- RCS: Remote Control System
- DUT Editor & Recipe Editor

## Specifications of A8 Automatic Probe Station

Main body	XY axis	Repeatability : $\leq \pm 1\mu\text{m}$
		Resolution: 0.1μm
		Probing area: 260 * 450 mm
	Z axis	Maximum speed : 200mm/s
		Repeatability : $\leq \pm 1\mu\text{m}$
		Resolution: 0.1μm
θ axis	Travel range: 0 ~ 80mm	
	Maximum speed : 80mm/s	
Loader	Cassette / Wafer Size	Rotation Range : $\pm 10^\circ$
Monitor		Resolution: 0.0001°
Facility Requirement		Φ150mm , Φ200mm
Dimensions & Weight		15 inch High-resolution color LCD
		Power : 50/60Hz AC 220V, CDA: 0.6 to 0.7Mpa , Vacuum: -70 to -90Kpa
		W*D*H: 1124mmL*1111mmW*925mmH , 1200 KG (standard).

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Website



WeChat

# SEMISHARE

# A8 Automatic Probe Station



Advanced wafer prober manufacturer





## SEMISHARE-A8 Automatic Probe Station

A8 is a new high-power probe with a temperature range from room temperature to +200 °C and supports the measurement of high voltage 3 kV (Tri-axis)/10 kV (coaxial) and 500A. It can test high-power chip characteristics, which can also be tested on thin wafers or TAIKO wafers.

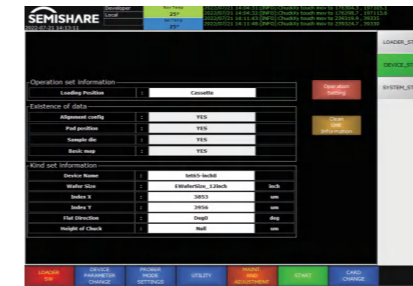
The innovative A8 probe has made new upgrades and improvements in technologies such as automatic wafer loading and unloading, micron-level full closed-loop motion control, automatic wafer contact, accurate visual calibration, high-speed feedback communication, and data information processing. The probe is equipped with a highly stable wafer testing technology.

## Product Features

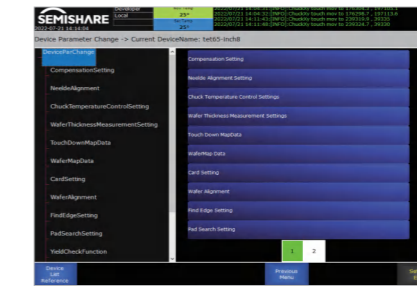
- Super high test precision and test speed, greatly improve productivity benefits
- Micrometer-level full closed-loop motion control
- 24X7 hours on-chip detection
- Small size, light weight and smaller footprint
- High voltage and high current test application
- Bernoulli arm support sheet

## Friendly Graphic User Interface

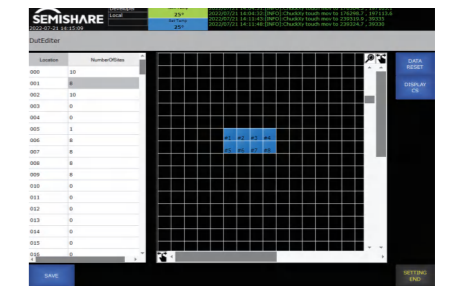
### Initial Information



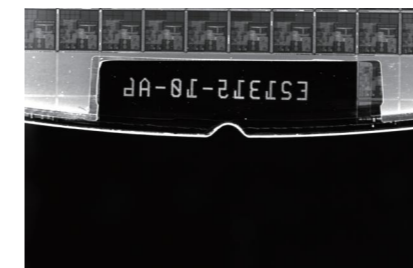
### Recipe Parameter Settings



### Multi DUT Location Edit



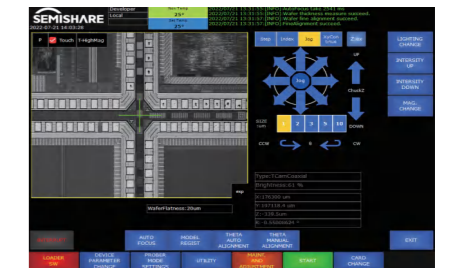
### Wafer ID Reading



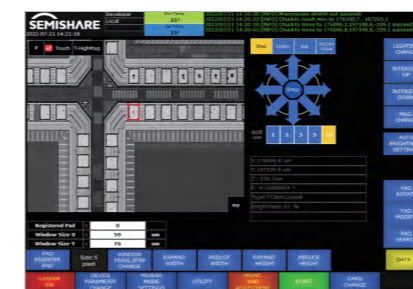
### Wafer Edge Measurement



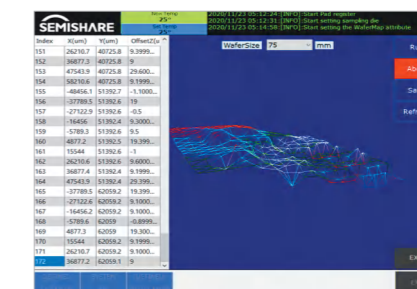
### Index & Z height



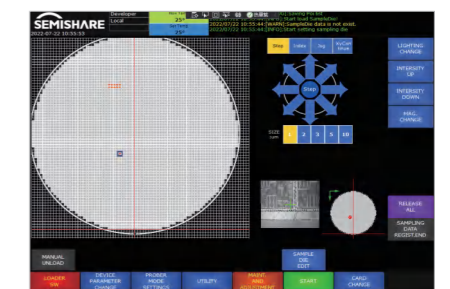
### PAD Registration



### Contact Compensation



### Real-time Wafer Map Data



## Software Functions

